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U.S. PATENT DOCUMENTS

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EXAMINER <i>Anita K. Glanko</i>	DATE CONSIDERED <i>3/22/04</i>
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

APPLN. NO.
09/989,898

APPLICANT:
Laurence M. C. Lai et al.

FILING DATE
19 November 2001

**GROUP
1765**

[illegible][illegible]

✓	Stanley Wolf and Richard N. Tauber, "Silicon Processing for the VLSI Era", Vol. 1, pp. 520-524, (1986).
↓	G. Daniel Woodring and Rufus R. C. Benton, "Chemical Blanking", Tool and Mfg. Engr., Vol. 52, pp. 87-90, (May 1964).
↓	"Chemical Milling for Thin Complex Parts", Metal Industry, Vol. 103, p. 188, (August 1963).

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